

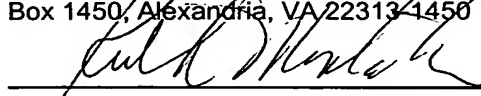


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/ Ruth Montalvo Date: 04/29/04

Customer No. 026418

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Docket No. GK-ZEI-3214 / 500343 20225

Applicant(s): Hans-Juergen DOBSCHAL, et al.

Application No.: 10/626,130

Group:

Filed: July 24, 2003

Examiner:

For: IMAGING SYSTEM FOR A MICROSCOPE BASED ON EXTREME ULTRAVIOLET (EUV) RADIATION

Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**SUPPLEMENTAL  
INFORMATION DISCLOSURE STATEMENT**

S I R:

Supplemental to the Information Disclosure Statement filed on January 15, 2003, enclosed are the following references that were previously omitted:

	Document Number	Date	Name and/or Country	English Translation
AO	102 20 815	11/20/2003	Germany	English Abstract only
AP	102 20 816	11/20/2003	Germany	English Abstract only

This submission is not an admission that the information disclosed in the documents is material to the patentability of the invention disclosed and/or claimed in the above-identified application.

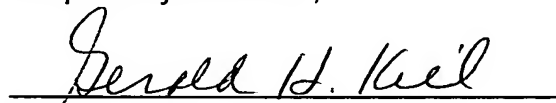
Respectfully submitted,

04/29/04  
JGHK:ram

Tel. (212) 521-5400

Enclosures:

PTO-1449  
2 documents  
2 English Abstract

  
Gerald H. Kiel - Reg. No. 25,116  
Reed Smith LLP  
599 Lexington Avenue  
New York, NY 10022-7650